EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	1	10/658168	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/10 10:58
L2	3	knoch-john$.in.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/10 10:58
L3	1	leek-deborah$.in.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/10 10:59
L4	2	strader-nathan$.in.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/10 10:59
L5	7328	LSI with logic$.as.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/10 10:59
L10	127	L5 and wafer and (process$3 with tool)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/10 11:02
L11	1	((pre-scan prescan) same defect) and wafer and (process$3 with tool) and ((post-scan postscan) same defect) and (display$3 same scatter same plot).clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/10 11:04
L12	341	702/81.ccls.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/10 11:05
L13	4	((pre-scan prescan post-scan postscan) same defect) and wafer and (process$3 with tool)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/10 11:04

IEEE Xplore®
RELEASE 2.1

Welcome United States Patent and Trademark Office

Search Results   BROWSE   SEARCH   IEEE XPLORE GUIDE

Results for "((defect and wafer and (process or processing) and tool and scan and semiconductor and   ☑e-mail
location)<..."
Your search matched **1** of **1325881** documents.
A maximum of **100** results are displayed, **25** to a page, sorted by **Relevance** in **Descending** order.

» Search Options

View Session History

New Search

Modify Search

| ((defect and wafer and (process or processing) and tool and scan and semiconductor | **Search** |

☐ Check to search only within this results set

Display Format: ◉ Citation   ○ Citation & Abstract

» Key

IEEE JNL	IEEE Journal or Magazine
IEE JNL	IEE Journal or Magazine
IEEE CNF	IEEE Conference Proceeding
IEE CNF	IEE Conference Proceeding
IEEE STD	IEEE Standard

[**view selected items**]   Select All   Deselect All

☐   1. **SEM/EDS analysis method for bare silicon particle monitor wafers**
Sullivan, N.; Arsenault, S.;
Advanced Semiconductor Manufacturing Conference and Workshop. 1994. AS
Proceedings. IEEE/SEMI
14-16 Nov. 1994 Page(s):293 - 296
Digital Object Identifier 10.1109/ASMC.1994.588281

AbstractPlus | Full Text: PDF(388 KB)   IEEE CNF
Rights and Permissions

Help   Contact Us   Privacy &

Indexed by
Inspec®

IEEE *Xplore*
RELEASE 2.1

Welcome United States Patent and Trademark Office

Advanced Search

BROWSE   SEARCH   IEEE XPLORE GUIDE

OPTION 1
Enter keywords or phrases, select fields, and select operators   **? Help**

[   ] **in** All Fields

[AND ▾] [   ] **in** All Fields

[AND ▾] [   ] **in** All Fields

» Note: If you use all three search boxes, the entries in the first two boxes take precedence over the entry in the third box.

OPTION 2
Enter keywords, phrases, or a Boolean expression   **? Help**

```
defect and wafer and (process or
processing) and tool and scan and
semiconductor and location
```

» Note: You may use the search operators <and> or <or>
  without the start and end brackets <>.
» Learn more about Field Codes, Search Examples, and Search Operators

» Publications
  ◉ Select publications
      ☑ IEEE Periodicals
      ☑ IEE Periodicals
      ☑ IEEE Conference I
      ☑ IEE Conference Pi
      ☑ IEEE Standards

» Other Resources (Availab
      ☑ IEEE Books

» Select date range
  ○ Search latest content u
  ◉ From year [All ▾]
              to [Present ▾]

» Display Format
  ◉ Citation   ○ Citatio

» Organize results
  Maximum [100 ▾]
  Display [25 ▾] resu
  Sort by [Relevance]
      In [Descending]

Help   Contact Us
© Copyright 20

Indexed by
Inspec